

Supporting Information

An efficiently enhanced UV-visible light photodetector with a Zn: NiO/p-Si isotype heterojunction

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Supplementary Figures

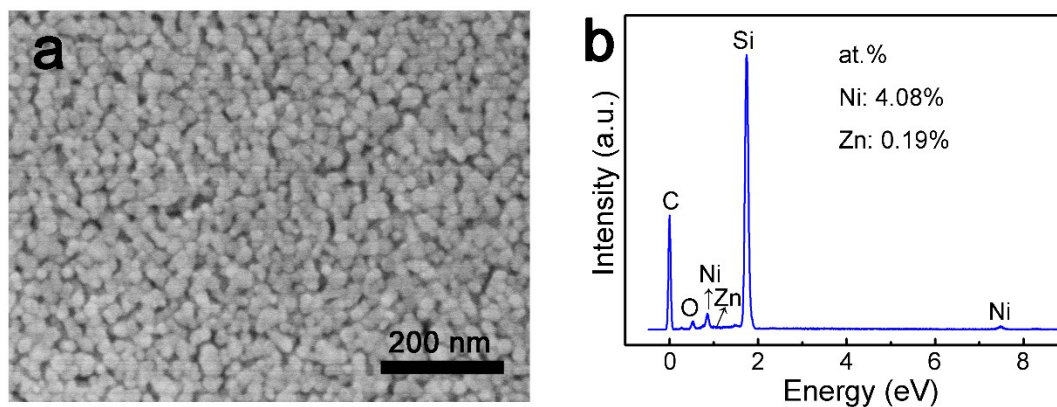


Figure S1. (a) SEM image of the NiO films without Zn doping. (b) EDX pattern taken from the Zn:NiO films.

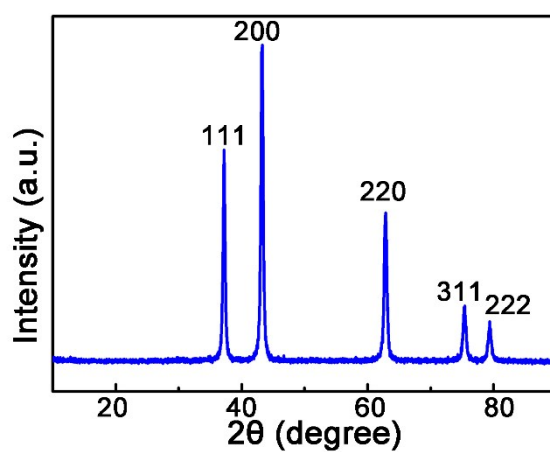


Figure S2. XRD patterns of the NiO films without Zn doping.

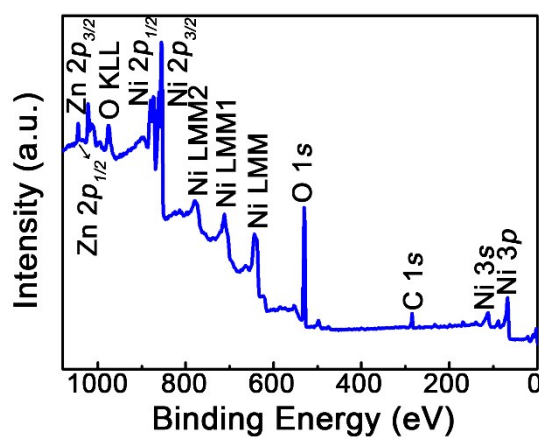


Figure S3. X-ray photoelectron spectroscopy of a full survey of the Zn:NiO/p-Si heterojunction.

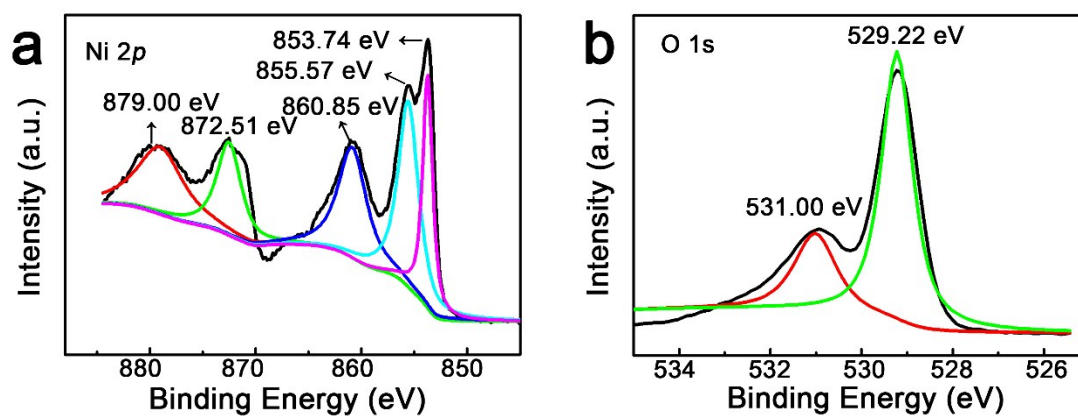


Figure S4. XPS spectra of the undoped NiO/p-Si heterojunction. High resolution XPS spectra for Ni (a) and O (b), respectively.

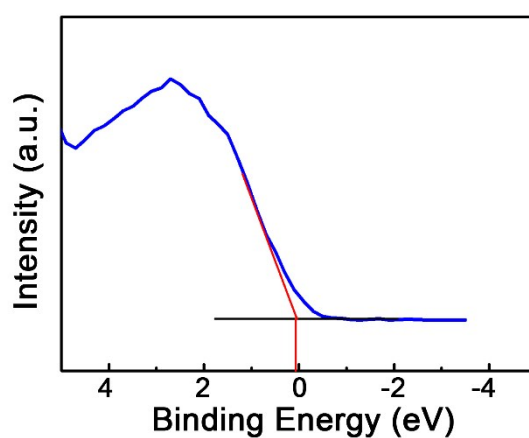


Figure S5. The valence band maximum of the cleaned Si substrate by analysing the XPS spectrum.

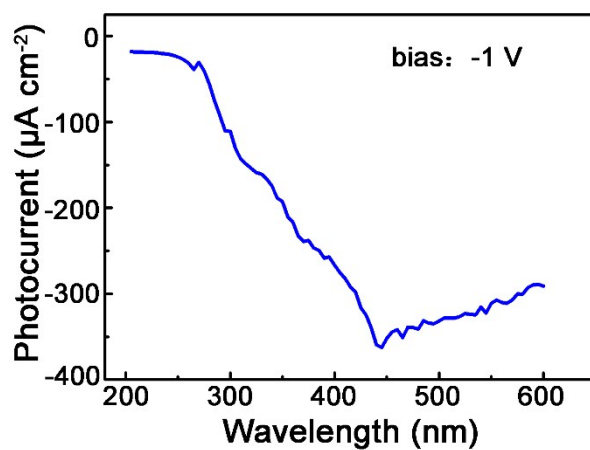


Figure S6. A photocurrent spectrum of the NiO/p-Si heterojunction photodetector with an applied bias of -1 V.

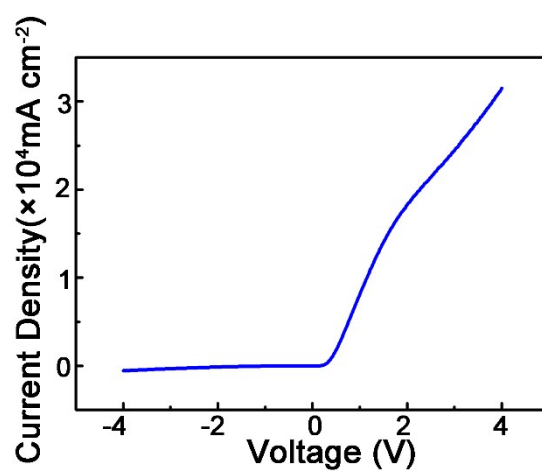


Figure S7. The J-V curve of the Zn:NiO/p-Si heterojunction device upon a bias from -4 V to 4V under dark.

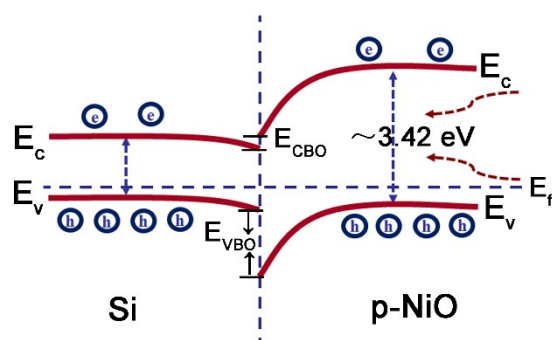


Figure S8. Band diagrams of the undoped NiO/p-Si heterojunction at the interface under a reverse bias.

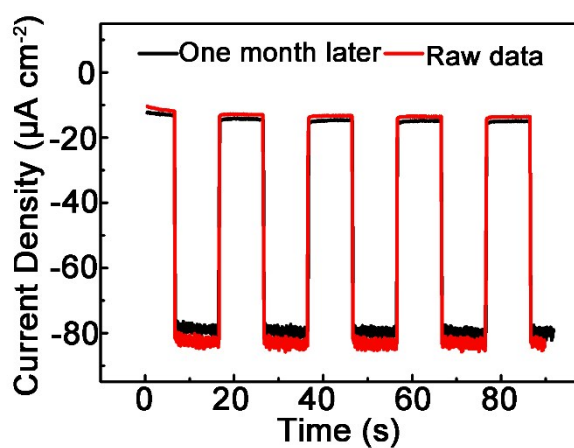


Figure S9. Photocurrent responses of the Zn:NiO/p-Si heterojunction photodetector at -1 V under 450 nm light illumination recorded before (raw data) and after one month.

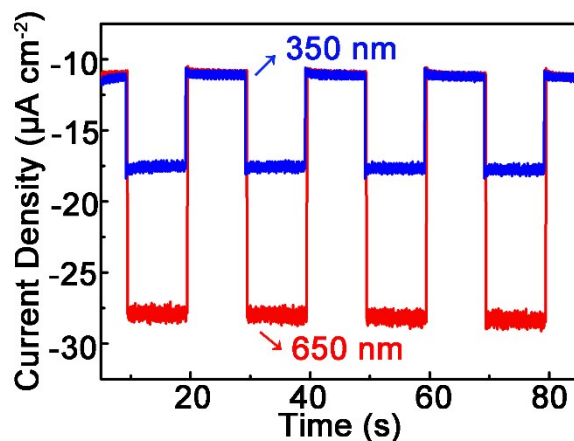


Figure S10. Photocurrent responses of the undoped NiO/p-Si heterojunction photodetector at -1 V with a light density of 0.5 mW cm^{-2} under 350 nm and 650 nm light illumination, respectively.

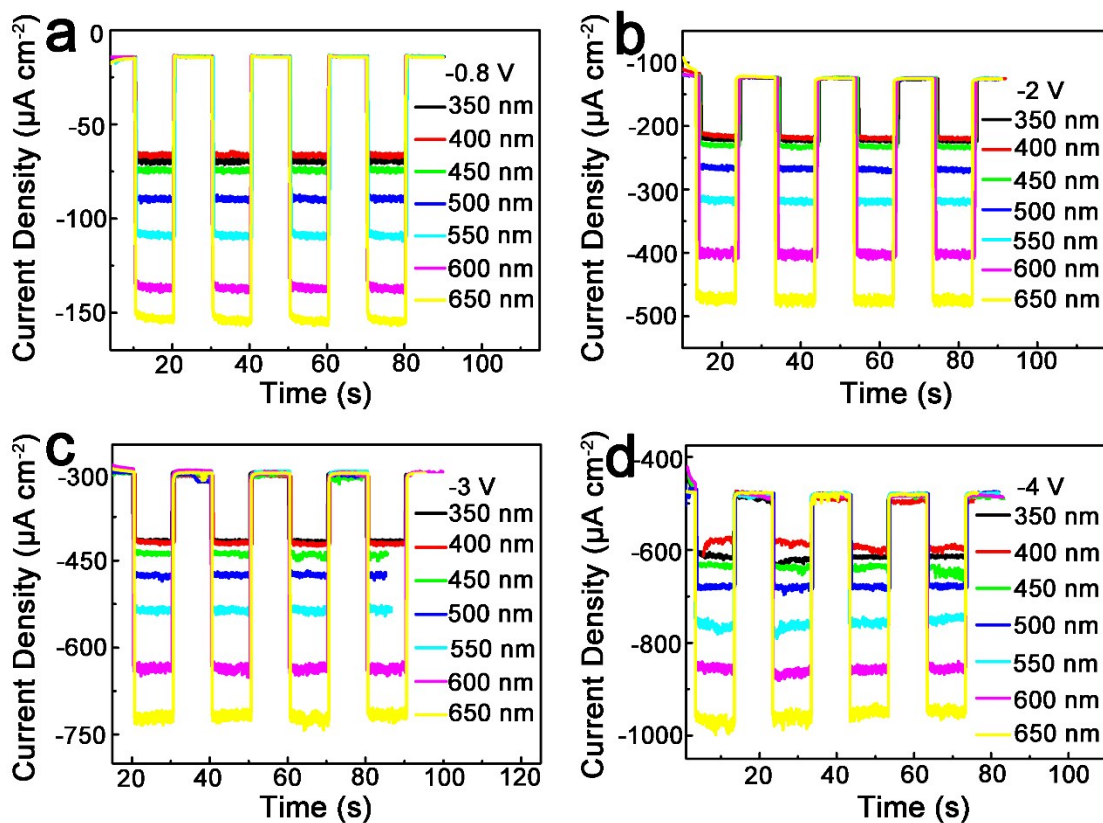


Figure S11. Photocurrent responses of the Zn-doped NiO/p-Si heterojunction photodetector under on/off light illumination at various applied voltage with a light density of 0.5 mW cm^{-2} .

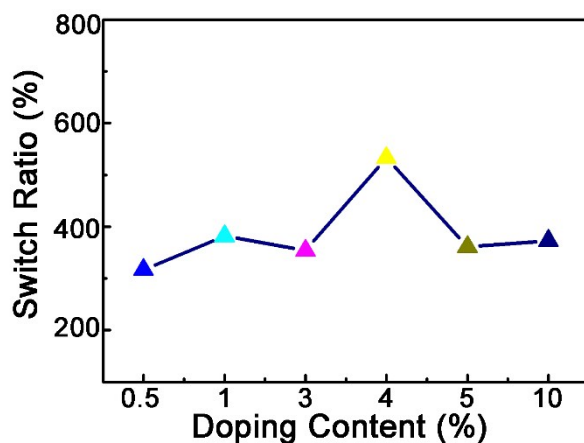


Figure S12. Switch ratio of the Zn:NiO/p-Si heterojunction photodiode with various Zn-doping content at an applied voltage of -1 V under 450 nm light illumination (0.5 mW cm^{-2}).

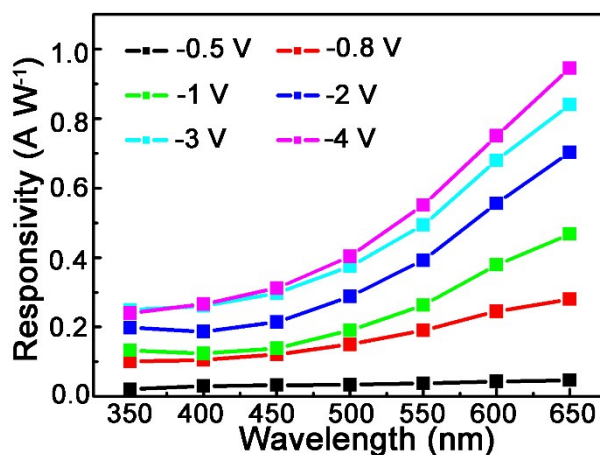


Figure S13. Spectral responsivity curves of the Zn-doped NiO/p-Si heterojunction photodetector in the range of $350\text{-}650 \text{ nm}$ under a reverse bias of -0.5 V , -0.8 V , -1 V , -2 V , -3 V and -4 V , respectively.

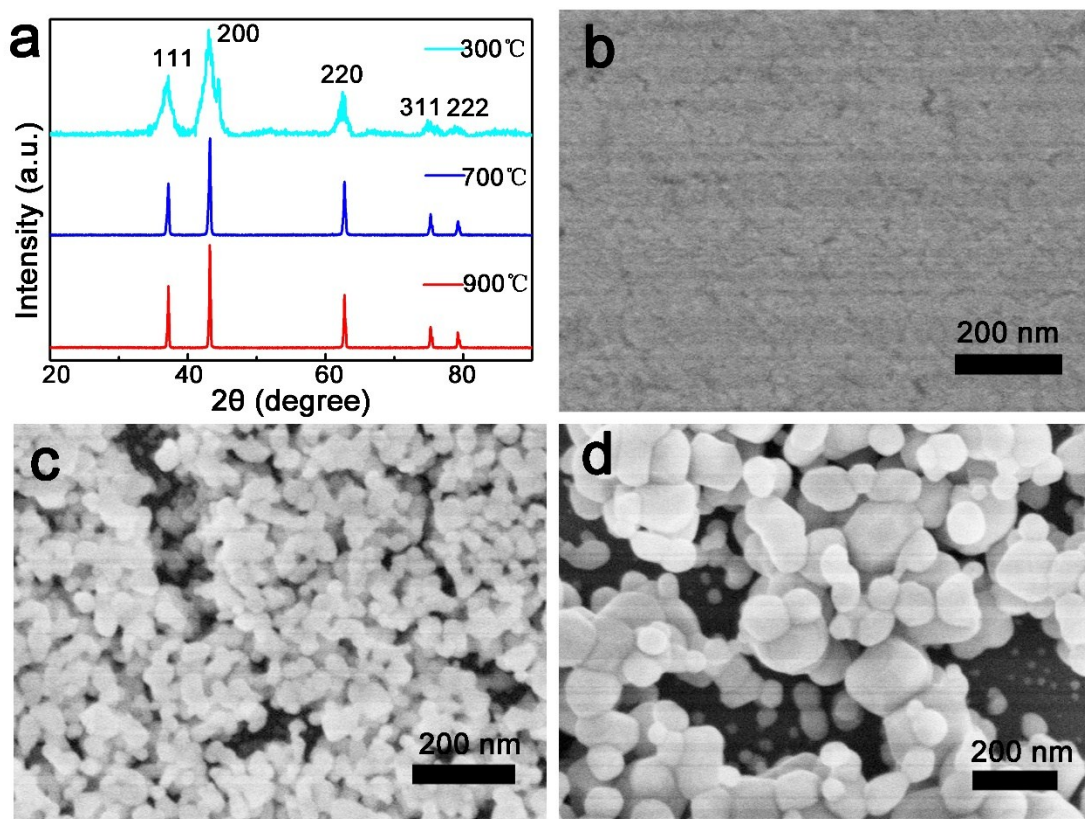


Figure S14. XRD patterns (a) of the NiO thin film sample annealed at 300 °C, 700 °C and 900 °C, respectively. SEM images showing the surface views of the NiO thin film on the Si substrates annealed at 300 °C (b), 700 °C (c) and 900 °C (d), respectively.

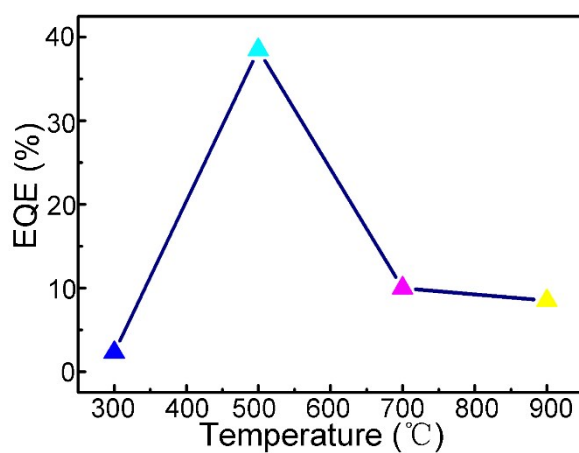


Figure S15. EQE of the Zn:NiO/p-Si heterojunction photodiode annealed at 300 °C, 500 °C, 700 °C and 900 °C, respectively, with an applied voltage of -1 V under 450 nm light illumination.

Supplementary Table

Table S1. The measurement parameter values obtained by Hall measurement with the Zn-doped and undoped NiO films.

Input value	I (nA)	B	D	D_T	MN	T (K)
	1.000	0.560	0.200	0.100	1000	300
Result			Undoped		Zn-doped	
Bulk concentration			8.459×10^{15}		2.906×10^{12}	
Mobility			1.850×10^1		5.730×10^1	
Resistivity			3.989×10^1		3.748×10^4	
Average Hall Coefficient			7.379×10^2		2.148×10^6	
AC Cross Hall Coefficient			6.593×10^2		3.651×10^5	
BD Cross Hall Coefficient			8.165×10^2		4.661×10^6	
Sheet Concentration			1.692×10^{11}		5.812×10^7	
Conductivity			2.507×10^{-2}		2.668×10^{-5}	
Magneto-Resistance			1.341×10^5		3.197×10^8	